

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

<b>Applicant(s):</b>	William G. America, et al.	<b>Examiner:</b>	Jack S. J. Chen
<b>Serial No:</b>	10/674,646	<b>Art Unit:</b>	2893
<b>Filed:</b>	September 30, 2003	<b>Docket:</b>	YOR920030320US1 (16868)
<b>For:</b>	PLASMA SURFACE MODIFICATION AND PASSIVATION OF ORGANO- SILICATE GLASS FILMS FOR IMPROVED HARDMASK ADHESION AND OPTIMAL RIE PROCESSING	<b>Dated:</b>	April 28, 2009

**Confirmation No.** 4797

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE UNDER 37 C.F.R. § 1.116**

Sir:


In response to the Office Action dated March 4, 2009, Applicants submit the following amendments and remarks for entry of record in the above-identified patent application.

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**CERTIFICATE OF ELECTRONIC FILING**

I hereby certify that this correspondence is being deposited with the United States Patent & Trademark Office via Electronic Filing through the United States Patent and Trademark Office e-business website on April 28, 2009.

Dated: April 28, 2009

  
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Leslie S. Szivos, Ph.D.